

2011-E14890/29

J04

SHAF 2009.10.05

SHARP KK

*JP 2011080798-A

2009.10.05 2009-231596(+2009JP-231596) (2011.04.21) G01N 27/12

Manufacturing method of chemical substance sensing element, involves including process of selecting material predicted to be suitable for surface modification material of electroconductive substrate from candidate material (Jpn)

C2011E14890

Addnl. Data: NGUYEN T Q, OTONASHI M, KAWATA T,
YAMANAKA M, HARA K, KASAI H, NAKANISHI H
2009.10.05 2009JP-231596

NOVELTY

The method involves adsorbing the candidate material made of metal phthalocyanine to an electron orbit of specified chemical substances related to coupling with specified chemical substances made of nitrogen monoxide. The adsorption energy with the specified chemical substances is computed. A process of selecting material predicted to be suitable for surface modification material (7) of an electroconductive substrate (2) is included from candidate material based on the computation.

USE

J(4-B, 4-C2B)

Manufacturing method of chemical substance sensing element.

ADVANTAGE

The sensitivity and performance of the chemical substance sensing element manufactured with respect to marker contained in the biometric information can be improved.

DESCRIPTION OF DRAWING

The drawing shows a schematic view of the chemical substance sensing element.

Chemical substance sensing element 1

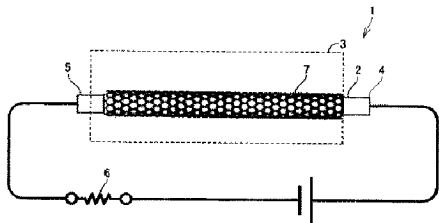
Electroconductive substrate 2

Sensing unit 3

Power supply 4

Surface modification material 7

JP 2011080798-A+



(13ppDwgNo.1/6)